

ABSTRACT

Provided is a technology capable of detecting abnormality in operation of support members of a substrate support device. An abnormality detection apparatus 20 for a substrate support device 10 includes a sensor 80 configured to detect vibration information or sound information generated when a plurality of support members 40 move, and a controller 70 configured to detect abnormality in the operation of the plurality of support members 40 based on the information detected by the sensor 80.

Selected Drawing: Fig. 1